

DESCRIPTION

Upright Metallurgical Microscopes are suitable to observe surface of opaque object or transparent object. They are equipped with UIS optical system and modularization function design so that provided excellent optical quality and operation performance, update system expediently and provided observation in reflected or transmitted and mixed illumination, polarizing observation, dark field observation.



Modes:

- *Bright Field*
- *Polarization*

This is ideal optical instrument for 2D Crystal Inspection. It can be used in Scientific Research & Universities for Metallography, Mineralogy, Precision Engineering etc.

TECHNICAL SPECIFICATION

Eyepiece	Wide Field 10X plan eyepiece pair and field of view number is $\Phi 22$ mm, diopter correction, Outer Diameter 30mm
Objective	Infinity Plan Achromatic Long Distance EPI objectives (Bright field): PLAN EPI 5X/0.12, Working Distance 26.1mm PLAN EPI 10X/0.25, Working Distance 20.2mm PLAN EPI 40X/0.60, Working Distance 3.98mm PLAN EPI 60X /0.70, Working Distance 3.18mm
Viewing Head	Binocular/ Trinocular inclined 30°, Rotatable 360°, Inter Pupillary Distance 53~75 mm.
Focusing system	Coaxial coarse/fine ergonomically low positioned focus system, with tension adjustable device, Manual Focus adjustment 23mm, minimum division of fine focusing: 2.0 μ m & per revolution rotation 0.2mm.
Nosepiece	Smooth ergonomics Quintuple (Backward ball bearing inner locating)
Stage	Mechanical Scratchless flat top ceramic coated stage, overall size : 210mmX140mm, X-Y moving range:63mmX50mm X-Y movement with right hand drop down co-axial controls
Koehler Illumination system	10W White LED OR Transmission: 6V30W halogen; Vertical / Reflecting: 6V30W halogen. Integrated field diaphragm, aperture diaphragm, Push-pull type analyser and polarizer
Power Requirement	Automatic voltage sensing (100V-240V) transformer with intensity control
Filter	Blue, Green, Yellow & ND50 Frosted
Condenser	Abbe Condenser NA 1.25 Rack & Pinion adjustable
Standard Accessories	Dust Cover, Operating Manual
Optional Accessories	PLAN EPI 20X , 50X Objectives

FEATURES

- UIS optical system and modularization function design
- Ergonomic design, low location of coaxial focus system
- Long working distance (no cover glass) and wide-field eyepieces
- Complete optional accessories.